

ATMI-513
Customer ID No.: 25559#7
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*[Signature]***IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re United States Patent Application of:)	
)	
Applicants: Ravi K. Laxman, et al.)	Confirmation Number: 9357
)	
Serial No.: 09/811,106)	Group Art Unit: 1621
)	
Date Filed: March 17, 2001)	Examiner: Samuel A. Barts
)	
Title: Low Dielectric Constant Thin Films and)	
Chemical Vapor Deposition Method of Making)	
Same)	

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[Signature: Maggie Chappuis]
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August 12, 2003
Date of Transmission

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**RESPONSE TO JULY 29, 2003 OFFICE ACTION DATED JULY 29, 2003 IN
U.S. PATENT APPLICATION 09/811,106**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to an Office Action dated July 29, 2003, applicant respectfully requests consideration of the subsequent remarks.